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	Application No.	Applicant(s)	THE STATE OF THE S
Notice of Allowability	10/751,169	LEE, DAE GUN	
Notice of Allowability	Examiner	Art Unit	
	David Nhu	2818	
The MAILING DATE of this communication appearable claims being allowable, PROSECUTION ON THE MERITS IS (herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGOR the Office or upon petition by the applicant. See 37 CFR 1.313	OR REMAINS) CLOSED or other appropriate comm GHTS. This application is	in this application. If not include nunication will be mailed in due	ed course. THIS
1. \boxtimes This communication is responsive to <u>12/30/03</u> .			
2. 🔀 The allowed claim(s) is/are <u>1-5</u> .			
3. $igotimes$ The drawings filed on <u>30 December 2003</u> are accepted by t	the Examiner.		
 4. Acknowledgment is made of a claim for foreign priority una) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have international Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" onoted below. Failure to timely comply will result in ABANDONMITHIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 5. A SUBSTITUTE OATH OR DECLARATION must be submitory in NFORMAL PATENT APPLICATION (PTO-152) which give (a) including changes required by the Notice of Draftsperson (a) including changes required by the attached Examiner's Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1.1 each sheet. Replacement sheet(s) should be labeled as such in the paper No./Mail Document regarding REQUIREMENT For the priority of the priority of the deposent attached Examiner's comment regarding REQUIREMENT For the priority of the priority of	been received. been received in Applicate cuments have been received from the cuments have been received from the communication to fix the communication to fix the cuments application. Itted. Note the attached Expression(s) why the oath the submitted. It be submitted. It is application. Amendment / Comment of the cuments of the cume	ion No ed in this national stage applicate the areply complying with the reconstruction of the drawings in the front (not the EFR 1.121(d). TERIAL must be submitted. Note the interest of the submitted. Note the submitted.	quirements OTICE OF
Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/06) Paper No./Mail Date 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ☐ Interview Paper No Paper No 7. ☑ Examiner	Informal Patent Application (PTC Summary (PTO-413), b./Mail Date s Amendment/Comment s Statement of Reasons for Allo	
		Jai Pa	

U.S. Patent and Trademark Office PTOL-37 (Rev. 1-04) Application/Control Number: 10/751,169 Page 2

Art Unit: 2818

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the change and/or additions be unaceptable to applicant, an amendment may be filed as provided by 37 CFR
 To ensure consideration of such an amendment, it MUST be submitted no later than

The application has been amended as follows:

Claim 1, "the hole pattern" should be -- a hole pattern-- because it lacks a clear antecedent basis.

REASONS FOR ALLOWANCE

2. Claims 1-5 are allowed.

the payment of the issue fee.

- 3. The following is an examiner's statement of reasons for allowance: None of the references of record teaches or suggests in claim 1: etching the etch stop layer by transferring a hole pattern into the etch stop layer; forming a first opening by etching the insulating layer down to a predetermined depth by transferring the hole pattern into the insulating layer; performing a pull back etching of an upper and side surface of the etch stop layer by a predetermined thickness for defining a second opening pattern; forming a second opening and a third opening in the insulating layer by etching the etch stop layer and the insulating layer until the etch stop layer is removed wherein the second opening and the third opening are etched by using the second opening pattern and the first opening as a mask respectively.
- 4. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the

Application/Control Number: 10/751,169

Art Unit: 2818

issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Page 3

CONCLUSION

5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure: Wang et al (6,383,919 B1): Method of Making a Dual Damascene Structure

Without Middle Stop Layer.

6. Any inquiry concerning this communication on earlier communications from the examiner should be directed to David Nhu, (571)272-1792. The examiner can normally be reached on Monday-Friday from 7:30 AM to 5:00 PM.

The examiner's supervisor, David Nelms can be reached on (571)272-1787.

The fax phone number for the organization where this application or proceeding is assigned is (703)872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

David Nhu

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November 25, 2004

DANID NHU PRIMARY EXAMINER